

FORM PTO-1449 INFORMATION DISCLOSURE CITATIONS IN AN APPLICATION	Atty Docket:	01-822	Serial #:
	Applicant:	Sukharev, Catabay	
	Filing Date:	2001.12.21	Group:

2021 U.S. PTO  
 10/036621  
 12/21/01

### U.S. PATENT DOCUMENTS

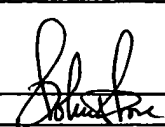
Examiner Initial	Cite #	Document Number	Date	Name	Class	Sub-Class	Filing Date
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### FOREIGN PATENT DOCUMENTS

Examiner Initial	Cite #	Document Number	Date	Country	Class	Sub-Class	Translation
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### OTHER NON-PATENT DOCUMENTS

Examiner Initial	Cite #	Author, title, date, pertinent pages, etc.
BR	1	Wang et al., <i>Stress-free polishing advances copper integrated with ultralow-k dielectrics</i> , Solid State Technology, pp.101-106, October 2001.

Examiner		Date Considered:	07/21/04
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.			